

Type	L #	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors
1	BRS L3	10618	((GLASS NEAR2 SUBSTRATE) WITH (SILICON SEMICONDUCTOR))	USPAT; EPO; JPO; Derwent	2000/04/13 13:26		n	0
2	BRS L4	668	3 AND (IRRADIAT?S2 WITH LASER WITH (FILM OR LAYER))	USPAT; EPO; JPO; Derwent	2000/04/13 13:34			0
3	BRS L5	186	4 AND (heat\$3 WITH crystalliz?S2)	USPAT; EPO; JPO; Derwent	2000/04/13 13:35			0
4	BRS L6	0	5 AND "vacuum chuck"	USPAT; EPO; JPO; Derwent	2000/04/13 13:35			0
5	BRS L7	558	3 AND (anneal\$3 WITH LASER)	USPAT; EPO; JPO; Derwent	2000/04/13 13:35			0
6	BRS L8	201	7 AND (CRYSTALLIZ?S2 WITH HEAT\$3)	USPAT; EPO; JPO; Derwent	2000/04/13 13:35			0
7	BRS L9	0	8 AND "vacuum chuck"	USPAT; EPO; JPO; Derwent	2000/04/13 13:36			0
8	BRS L10	143	5 AND 8	USPAT; EPO; JPO; Derwent	2000/04/13 13:41			0
9	BRS L11	46	10 AND vacuum	USPAT; EPO; JPO; Derwent	2000/04/13 13:49			0
10	BRS L12	0	11 AND chuck	USPAT; EPO; JPO; Derwent	2000/04/13 13:41			0
11	BRS L13	777	269/21.ccls.	USPAT; EPO; JPO; Derwent	2000/04/13 13:53			0
12	BRS L14	0	10 AND 13	USPAT; EPO; JPO; Derwent	2000/04/13 13:54			0
13	BRS L15	0	10 AND ("suction means" "vacuum holder" "vacuum support")	USPAT; EPO; JPO; Derwent	2000/04/13 13:56			0

\* VDC. holding of substrate

/ sucking on substrate)

not fought with

best crystallization

1218 treatment of crystal

EAST sub vacuum. WSP

09/308, 823

11

Type	L #	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors
1	BRS L1	1041	(((((INSULATING OR GLASS) WITH SUBSTRATE) WITH ("GALLIUM ARSENIDE" OR GAAS OR SILICON OR SEMICONDUCTOR))) AND ((IRRADIAT?\$2 WITH LASER) WITH (FILM OR LAYER)))) AND (@AD < "19960718")) AND (@AD < "19950719"))	USPAT; EPO; JPO; Derwent	2000/04/13 09:41			0
2	BRS L2	95	1 AND (heat\$3 WITH crystalliz?\$3)	USPAT; EPO; JPO; Derwent	2000/04/13 09:44			0

rev 4

L13 is

vechnok.wsp

09/308, 523

EST sub

patatys.wsp